

ME-03-010

February 27, 2004

To: Commissioner for Patents
P.O.Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/742,120 12/19/03 |
Chih Kiong Terence Gan et al.
SINGLE-CRYSTAL-SILICON 3D
MICROMIRROR
| _____ |

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service as first class
mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450, on March 1, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date S.B. Ackerman 3/1/04

The following two U.S. Patents discloses mirrors fabricated from thick single crystal silicon and actuators fabricated from thin single crystal silicon:

- 1) U.S. Patent 6,563,106 to Bowers et al., "Micro-Electro-Mechanical-System (MEMS) Mirror Device and Methods for Fabricating the Same."
- 2) U.S. Patent 6,556,737 to Miu et al., "Silicon Bulk-Micromachined Electromagnetic Fiber-Optics Bypass Microswitch."

U.S. Patent 6,504,643 to Peeters et al., "Structure for an Optical Switch on a Substrate," discusses having a single crystal silicon mirror and MoCr electrostatic and parallel plate actuators requiring high voltage.

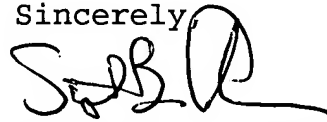
U.S. Patent 6,480,320 to Nasiri, "Microelectromechanical Mirror and Mirror Array," describes thick single crystal silicon micromirrors and silicon-on-insulator (SOI) single crystal silicon electrostatic and parallel plate actuators requiring high voltage.

U.S. Patent 6,386,716 to Hagelin et al., "Optical Mirror System with Multi-axis Rotational Control," discloses polysilicon micromirrors and electrostatic actuators requiring high voltage.

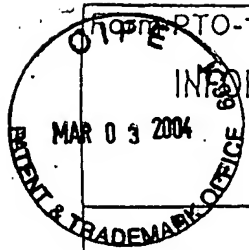
The article "Micromirrors for Adaptive-optics Arrays," by Michael A. Helmbrecht et al., Transducers '01 Eurosensors XV, June 2001, describes micromirrors built using wafer bonding techniques.

The artical "Three-dimensional structures obtained by double diffusion and electrochemical etch stop," by S. Marco et al., Journal of Micromech. Microeng. 3, (1993), pp. 141-142, discloses a two-step silicon layer method of forming non-uniform diaphragms and bridges.

Sincerely

A handwritten signature in black ink, appearing to read 'SBA', with a long horizontal flourish extending to the right.

Stephen B. Ackerman,
Reg. No. 37761



PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION. (Use several sheets if necessary)	Doc. # (Number of Copies)	Application Number
	IME-03-010	10/742,120
	Applicant: Chih Kiong Terence Gan et al.	
	Filing Date: 12/19/03	Group Art Unit

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILED DATE & APPROXIMATE
	6563106	5/13/03	Bowers et al.	250	216	8/14/01
	6556737	4/29/03	Min et al.	385	16	11/2/00
	6504643	1/7/03	Peeters et al.	359	290	9/28/00
	6480320	11/12/02	Nasiri	359	291	2/7/01
	6386716	5/14/02	Hagelin et al.	359	871	6/11/01

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Portion of Pages, Etc.)

-	"Micromirrors for Adaptive-optics Arrays", by Michael A. Helmbrecht et al., <u>Transducers '01 Eurosensors XV</u> , June 01.
-	"Three-dimensional structures obtained by double diffusion and electrochemical etch stop" by S. Marco et al., <u>Jrnl of Micromech. Microeng.</u> 3 (1993), pp. 141 - 142.

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.